

NEWS RELEASE

Hitachi HighTech

HITACHI

Hitachi High-Technologies Corporation

24-14, Nishi-shimbashi 1-chome, Minato-ku, Tokyo 105-8717, JAPAN

June 22, 2011

Preliminary Injunction Order against FEI Japan

On June 15, 2011, Tokyo District Court issued a preliminary injunction ordering FEI Japan not to make, sell, assign, lease, offer for assignment or lease, display for the purpose of assignment or lease, or import the products below. The order was to grant Hitachi High-Technologies' motion, which was filed December 15, 2010, in Tokyo District Court. In the motion, Hitachi High-Technologies alleged FEI's FIB/SEM apparatus* infringed Japanese patent No. 2,774,884 ("884 patent") related to Micro-Sampling technology using Focused Ion Beam, and sought a preliminary injunction against FEI Japan.

"Quanta 3DFEG"

Equipped with a probe (Omniprobe or Autoprobe) and GIS apparatus* with Platinum Deposition gas, Tungsten Deposition gas, or Carbon Deposition gas.

In addition, regarding 884 patent, Tokyo Customs has already officially accepted Hitachi High-Technologies' motion to suspend importation for the products below.

"Helios NanoLab 450S", "Quanta 3D200i" and "Quanta 3DFEG 600"

Equipped with Omniprobe and GIS apparatus.

Hitachi High-Technologies considers our intellectual property rights as an important management resource, and will make every effort to protect such rights.

[Note]

*FIB/SEM apparatus: Focused Ion Beam apparatus equipped with Scanning Electron Microscope

*GIS apparatus: Gas Injection System

Media Inquiries:

Corporate Communications Department

CSR Division

Aiko Matsumoto/Reiko Takeuchi Tel: +81-3-3504-3258